

Large periphery AlGaIn/GaN Metal-Oxide-Semiconductor Heterostructure Field Effect Transistors on SiC Substrates

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The development of new generations of GaN/AlGaIn microwave power electronics requires Field-Effect Transistors (FETs) with low gate leakage and superior pinch-off characteristics, specifically at elevated temperatures. These properties directly impact the devices drain breakdown voltage, rf- performance, and noise figure. In the past, several groups have attempted to achieve gate leakage suppression and superior pinch-off characteristics using the Metal-Insulator FET (MISFETs) or Metal-Oxide FETs (MOSFETs) device approach. However, the performance level of all these insulated gate devices was well below that of the state-of-the-art AlGaIn/GaN HFETs. We now report on a novel AlGaIn/GaN Metal-Oxide-Semiconductor Heterostructure Field Effect Transistors (MOS-HFET) on SiC substrate. Our MOS-HFET design combines the advantages of the MOS structure suppressing the gate leakage current and AlGaIn/GaN interface providing high-density 2D electron gas (2DEG) channel.

We demonstrate that the dc- and microwave performance of the MOS-HFETs is superior to that of conventional AlGaIn/GaN HFETs fabricated on the same GaN-AlGaIn HEMT wafer with $n_s=1 \times 10^{13} \text{ cm}^{-2}$ and mobility of $1200 \text{ cm}^2/\text{V}\cdot\text{sec}$. This points to the high quality of SiO₂/AlGaIn heterointerface. For devices with a source - drain separation of $5 \mu\text{m}$ and a gate length of $2 \mu\text{m}$ the maximum device current close to 1.3 A/mm was measured at a positive gate bias of $+9 \text{ V}$. Further, the devices completely pinched off around -9 V . The MOS-HFETs could also operate at positive gate biases higher than $+10 \text{ V}$ and the gate leakage current was more than six orders of magnitude smaller than that for the conventional AlGaIn/GaN HFETs (Please see Figure 1 and 2). The MOS-HFETs exhibited stable operation at elevated temperatures up to $300 \text{ }^\circ\text{C}$ with excellent pinch-off characteristics. A pinch-off current as low as 0.15 nA/mm at room temperature and $38 \mu\text{A/mm}$ at $250 \text{ }^\circ\text{C}$ was measured at a gate voltage $V_g = -15 \text{ V}$ and at a drain bias of 10 V . Even at $300 \text{ }^\circ\text{C}$ the pinch-off current remains 10 mA/mm , which is about 100 times less than the maximum saturation current. Up to $300 \text{ }^\circ\text{C}$ no degradation was observed in the maximum saturation current.

For the devices of our study with a gate length of $2 \mu\text{m}$, we also measured the current gain as a function of frequency. The cutoff frequency (f_t) values of 8.2 GHz and 5.9 GHz were measured for the MOS-HFET and the HFET, respectively. Note this value of the ($f_t L_g$) product of $16.4 \text{ GHz}\cdot\mu\text{m}$ for MOS-HFET also compares very favorably with the highest reported values of state-of-the-art AlGaIn/GaN HFETs. We also compared the maximum output RF power for both MOS-HFET and HFET devices. Under identical bias conditions, 30 V drain bias and -1.5 V gate bias, the maximum power of about 2 W/mm was measured for both device types. Our data thus clearly indicates that the MOS-HFET device approach preserves the high frequency performance.

We have also demonstrated a large periphery MOSHFET device for the first time. The saturation current, transconductance and the maximum rf-output power scale linearly with gate width upto 1 mm . (see Figures 3 and 4). Even for the large periphery devices the gate leakage currents were 4-6 orders below those for HFETs. The f_t values also did not vary with the device periphery. This shows an excellent potential for using the MOSHFET device approach for high power microwave applications.

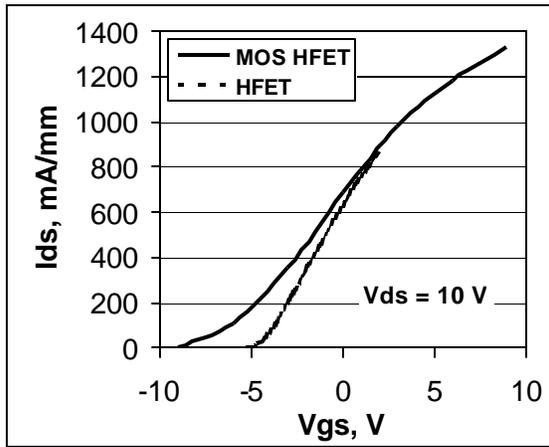


Figure 1. The saturation-current for the MOS-HFET and base-line HFET devices. Drain to source voltage is 10 V. The gate length is 2 μm ; the drain to source opening is 5 μm

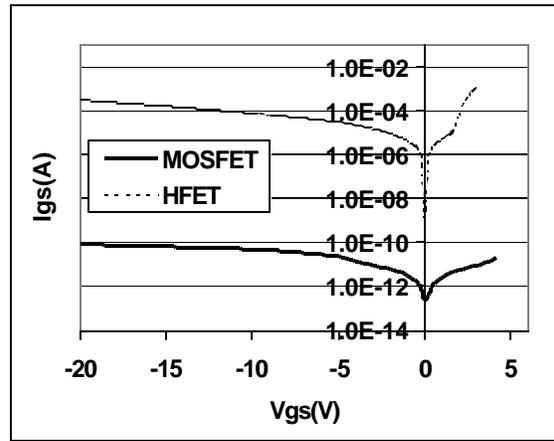


Figure 2. Gate leakage current for the MOS-HFET and the base-line HFET

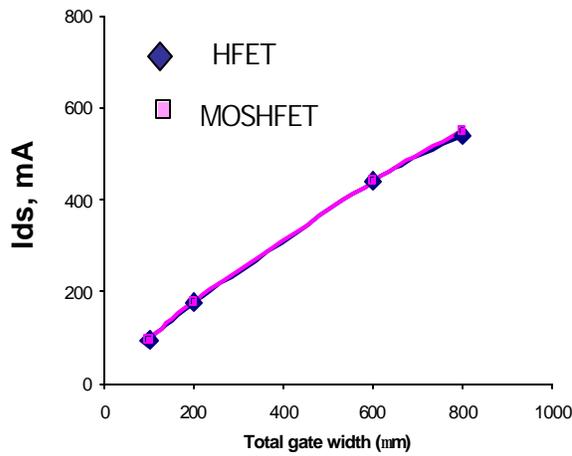


Figure 3. MOSHFET and HFET source-drain current versus gate width

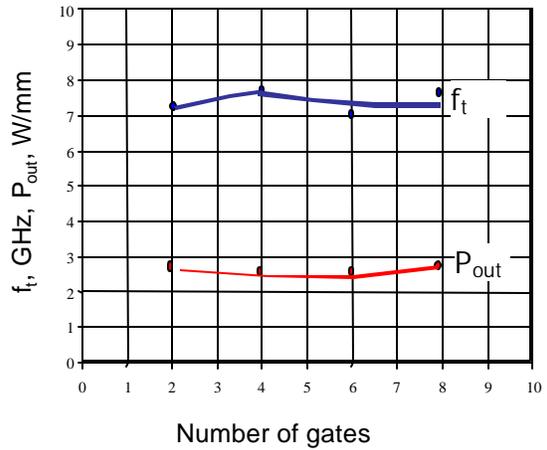


Figure 4. MOSHFET f_t and P_{out} (2GHz) versus number of gates